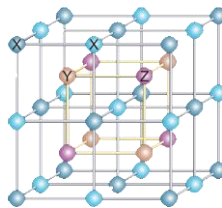




Heusler Compounds: CPP GMR, MRAM and making them by sputtering

Matthew Carey
Spin Transfer Technologies

30 July, 2015



(very) Partial list of team members (IBM→Hitachi→HGST/WD)

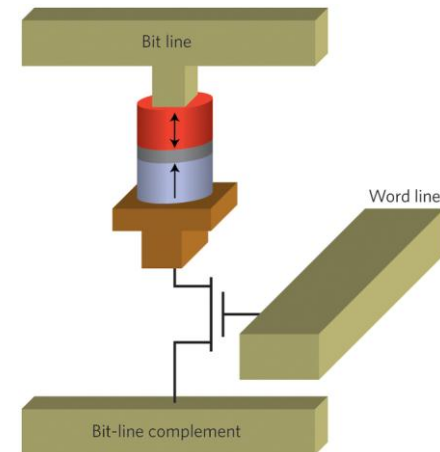
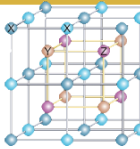


- Bruce Gurney
- Jeff Childress
- Stefan Maat
- Jordan Katine
- Young-Suk Choi
- John Read
- Brian York
- Liz Brinkman
- Tomoya Nakatani
- Phil Rice (IBM)
- Andrew Kellock (IBM)

MRAM Basics



- MRAM: Magnetic Random Access Memory
- Memory stored in “free layer” magnetization
 - Written by Spin Transfer Torque
- Memory read by tunneling magnetoresistance (TMR)

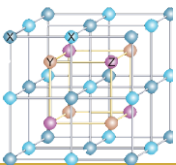
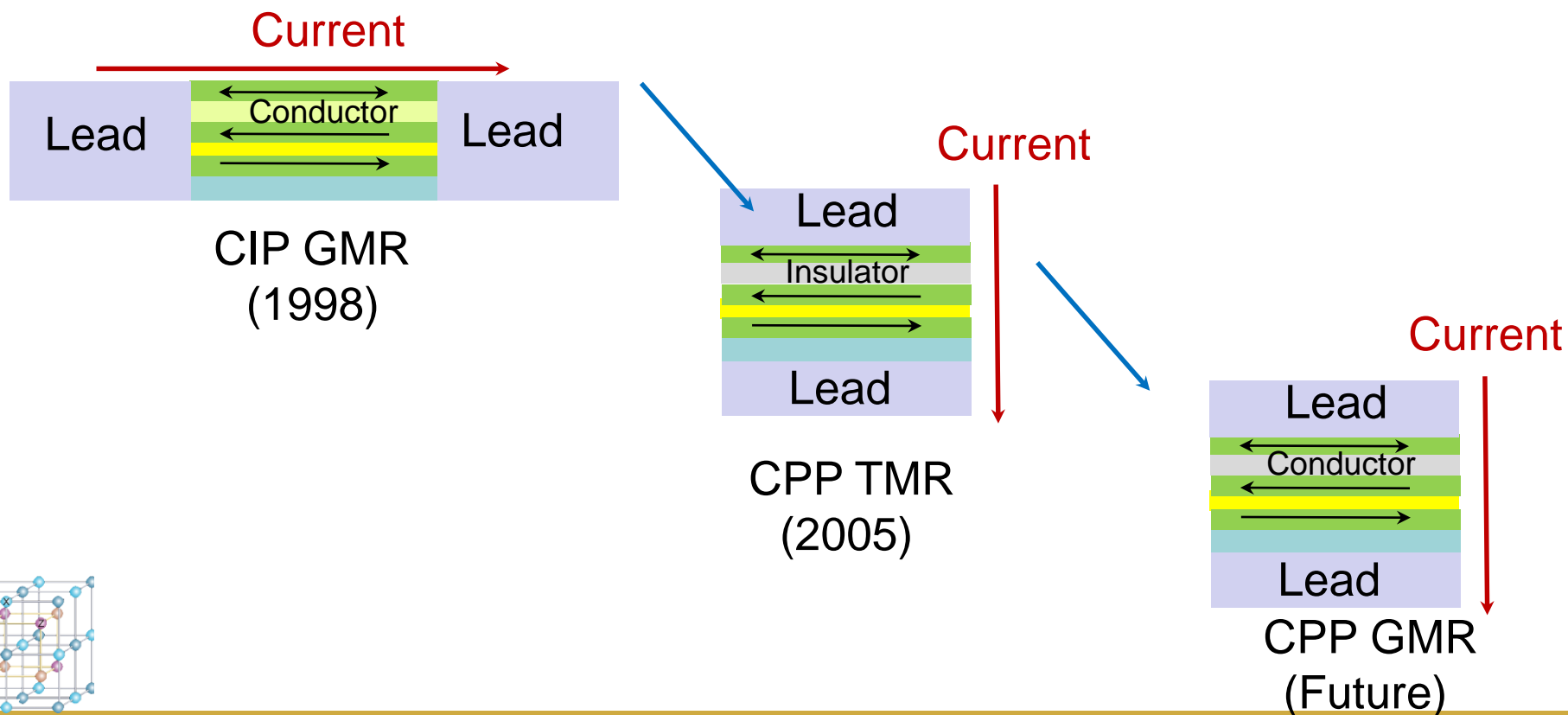


Kent and Worledge:
Nature Nanotechnology
10, 187–191 (2015)

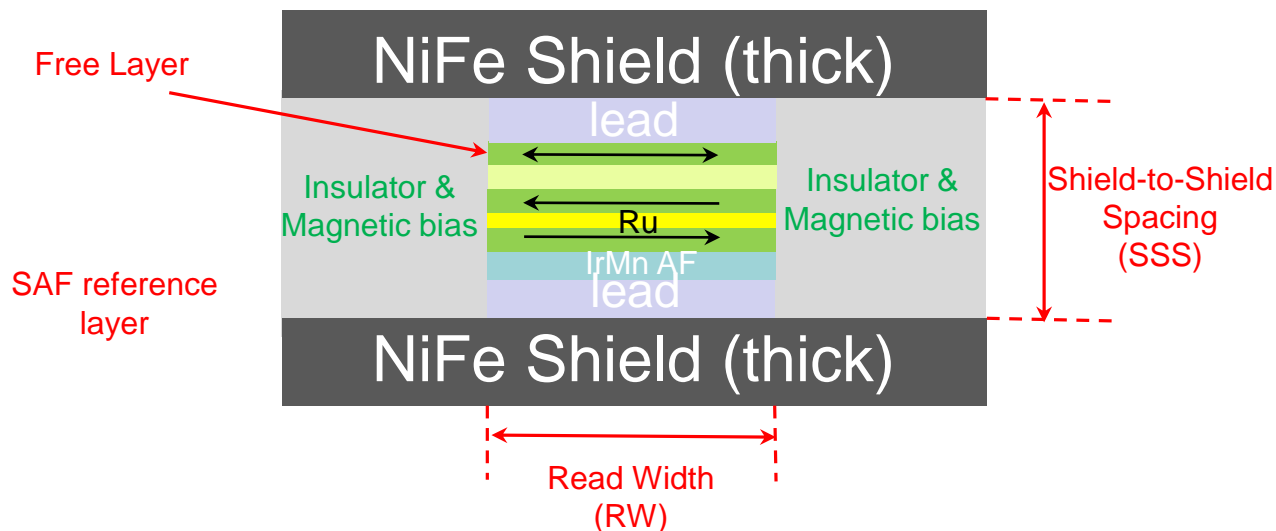
CPP-GMR Basics



- CPP-GMR: **C**urrent **P**erpendicular to the **P**lane **G**iant **M**agnetoresistance
- Possible replacement for TMR (**T**unnelling **M**agnetoresistance) read sensors

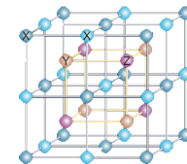


Anatomy of CPP-GMR read sensor

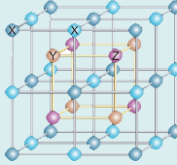


Magnetic layer thicknesses are very limited by head requirements

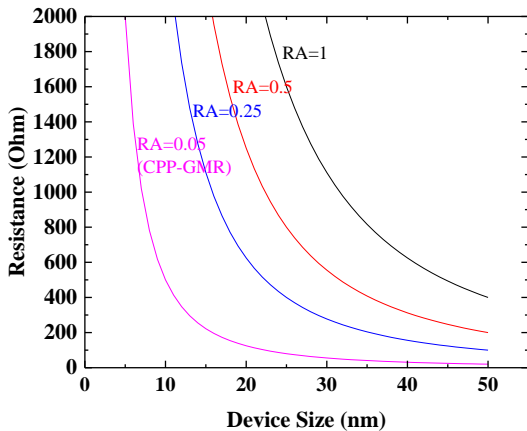
- Sensor resolution (density) is determined by RW and SSS
 - SSS limits overall stack thickness (@ 1TB/in², SSS<25nm)
- Read heads are flux sensors, not field sensors
 - Free layer moment must match flux from media
- Reference layer Stability limits magnetic moments
 - AF exchange coupling and RKKY coupling through Ru fall off as 1/moment



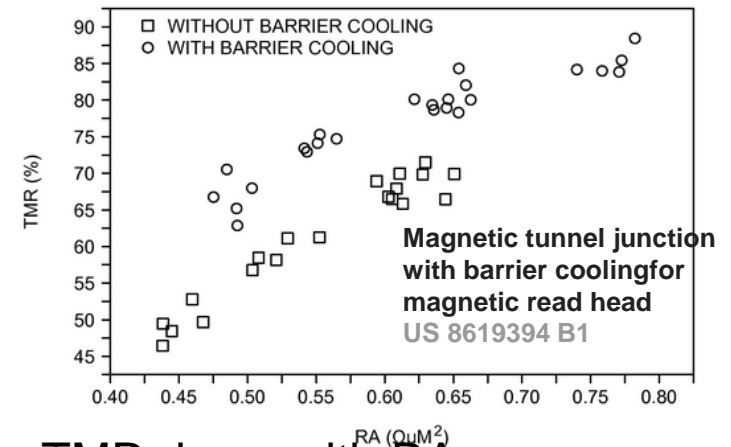
Why CPP-GMR?



- Big driving factor: Low RA
 - Qunwen Leng's presentation
 - As density increases, device size decreases
 - Resistance and Johnson noise increase
 - Requires low RA MTJ's
 - TMR decreases
 - Coupling fields increase
- GMR RA is about $0.05 \Omega\text{-}\mu\text{m}^2$



Resistance of square devices:
Climbing rapidly for $RA > 0.25$

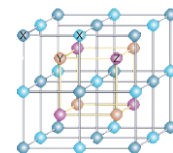


TMR drops with RA
→ Novel techniques to increase

Heusler Compounds



- I prefer “compound” not “alloy”
- Discovered in 1903 by Friedrich Heusler
 - He mixed “nonmagnetic” Cu, Mn and Sn to get a magnetic compound
- In 1983 de Groot calculated that some Heusler’s could be half-metallic
- Heuslers are ordered compounds
 - Half Heusler: XYZ
 - Full Heusler: X₂YZ
- Chemically ordered → each atom has a specific location on the lattice

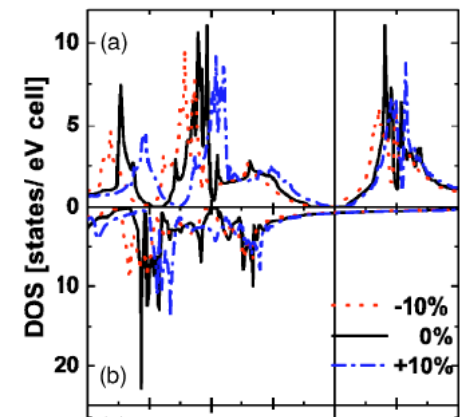


Half Metals

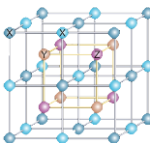


- Electrons with one spin direction are metallic.
 - No gap at Fermi energy
- Electrons in the other spin direction are semiconducting
 - Gap at Fermi Energy
- Polarization: $p = (n_{\uparrow} - n_{\downarrow}) / (n_{\uparrow} + n_{\downarrow})$
 - Where $n_{\uparrow}(n_{\downarrow})$ is the majority (minority) DOS at the E_{Fermi} .
 - Half metals have 100% spin polarization
 - **Should give infinite TMR or CPP-GMR**
 - **Low damping**
 - Lack of spin mixing channel
- Half metals are theoretically predicted
 - Zero temperature calculations
 - Real Heuslers are high spin polarization but perhaps not 100%
 - And that's OK—high polarization is good!
- Let me say this again:
 - **Low Damping**

PHYSICAL REVIEW B 70, 205114 (2004)



NiMnSb Density of States (DOS)
Majority state (top): semiconducting
Majority state (bottom) metal
Shown with and without $\pm 10\%$ strain



Heuslers: advantages and challenges



MRAM

Reduce Switching Current

- High spin polarization (P) \rightarrow highly susceptible to spin torque
- Switching current proportional to damping
 $Jc_0 \propto \alpha$

Most Heuslers are low anisotropy/in-plane magnetization

Must withstand 400°C anneal

Needs to be made thin

CPP-GMR

Higher GMR

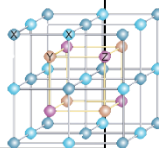
- High spin polarization:
 $\Delta RA \sim 1 \text{ m}\Omega\text{-}\mu\text{m}^2$ (std metal)
 $\Delta RA > 7 \text{ m}\Omega\text{-}\mu\text{m}^2$ (Heusler)

Most Heuslers are low anisotropy/in-plane magnetization

Low damping high $P \rightarrow$
Highly susceptible to spin torque

Anneal limited to $< 300^\circ\text{C}$

Needs to be made thin



Compounds not alloys: Chemical ordering

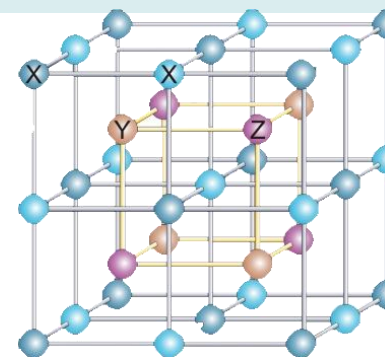


- Each atom has a specific location on the lattice
 - L2₁ structure: true full Heusler
 - X₂YZ where X, Y and Z positions are clearly defined
 - B2 structure: X and Y can substitute, Z specified
 - B2 can give Half-metal band structure
 - It can be very hard to determine B2 vs L2₁
 - Consider Co₂MnGe and Co₂FeAl
 - Z_{Mn}=25, Z_{Fe}=26, Z_{Co}=27
 - I.e. very little contrast for XRD or TEM

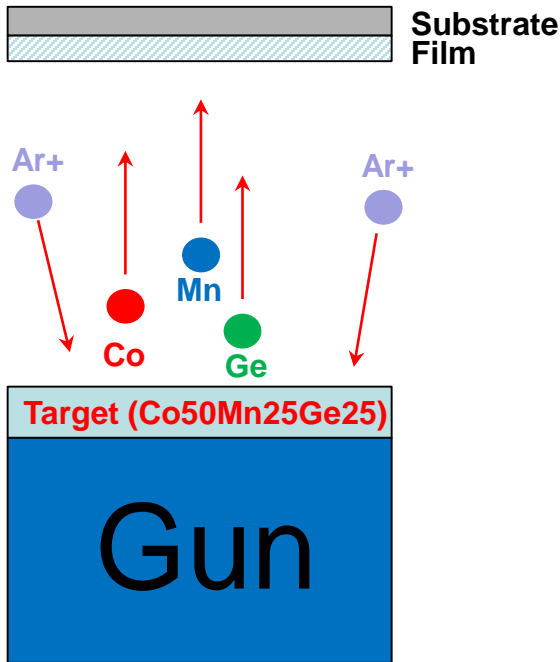
L2₁ structure: X₂YZ

where X, Y and Z occupy specific sites on the lattice.

B2 has X and Y substitution

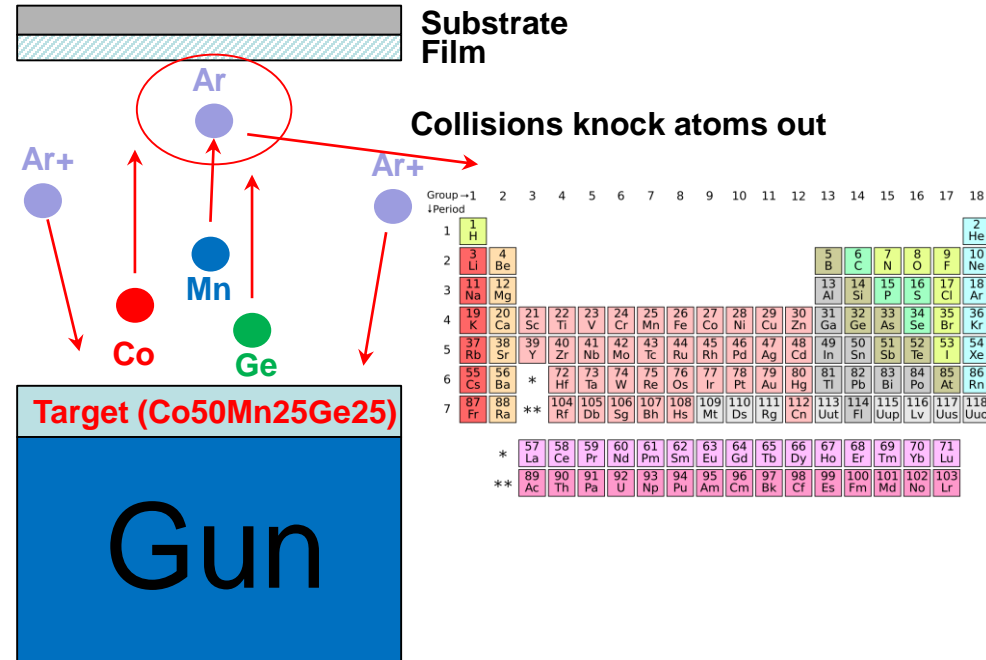


Sputtering: composition shift



Ideal case:
 Ar ions hit target
 Target atoms fly to substrate
 → **Film composition = target composition**

In real life film composition <> target composition



One reason for composition shift:
 Gas phase scattering
 Pressure dependent (higher pressure → more shift)
 Gas dependent
 billiard ball model
 when $\text{Mass}(\text{gas}) \sim \text{Mass}(\text{atom}) \rightarrow$ more scattering
 changing gas mass changes shift

Sputtering Heuslers: single target

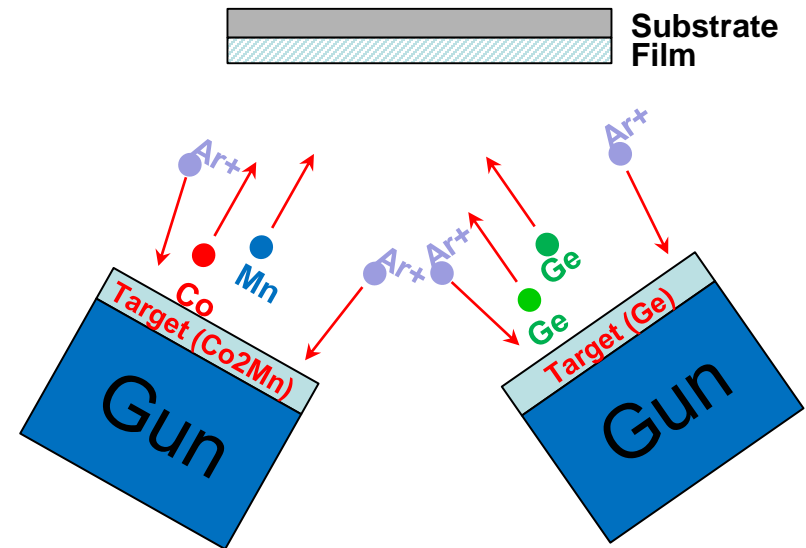


- Most simple method: single target
 - Process flow:
 - Order target of desired Heusler composition
 - Test target composition
 - Order new target, adjusting for composition shift
 - Dial in composition, make films, do experiments
- I don't use this method: why?
 - Heusler targets were not available when I started
 - Heusler targets can be difficult to work with
 - Magnetic → targets be thinner → less utilization
 - Compounds → brittle → fragile
 - Less flexible than cosputtering

Cosputtering



- Sputter from 2 or 3 targets
 - e.g. Co_2Mn and $\text{Ge} \rightarrow \text{Co}_2\text{MnGe}$
- Advantages?
 - Targets easier to manufacture
 - Targets are less fragile
 - Targets are thicker (0.25" vs. 0.125")
 - Can vary "Z" element (X_2YZ)
 - E.g. Ge rich or Ge poor
 - Can easily change "Z" element
 - Change from $\text{Co}_2\text{MnGe} \rightarrow \text{Co}_2\text{MnSi}$ with a simple target change
 - Make quaternary: E.g. $\text{Co}_2\text{Mn}(\text{Ge}_x\text{Si}_{1-x})$ with three targets
- Things to watch out for
 - Mn targets can be brittle (>40at% Mn)
 - Mn is an oxygen getter
 - Mn alloy targets can have high oxygen content
 - Oxygen can make ordering more difficult
 - Pure Mn targets are difficult to obtain
 - Brittle
 - Oxygen contamination
 - Target can oxidize
 - Other targets can be difficult to make
 - E.g. Ge-Ga (Ge and Ga do not alloy)



Example: using cosputtering to optimize Ge concentration



- Ge-rich Co_2MnGe_x gave better GMR:
 - $\text{Co}_2\text{MnGe}/\text{Cu}/\text{Co}_2\text{MnGe}$ spin valve
 - Stoichiometric Ge = 25%
 - GMR increases up to 28% Ge

093912-7 Carey et al.

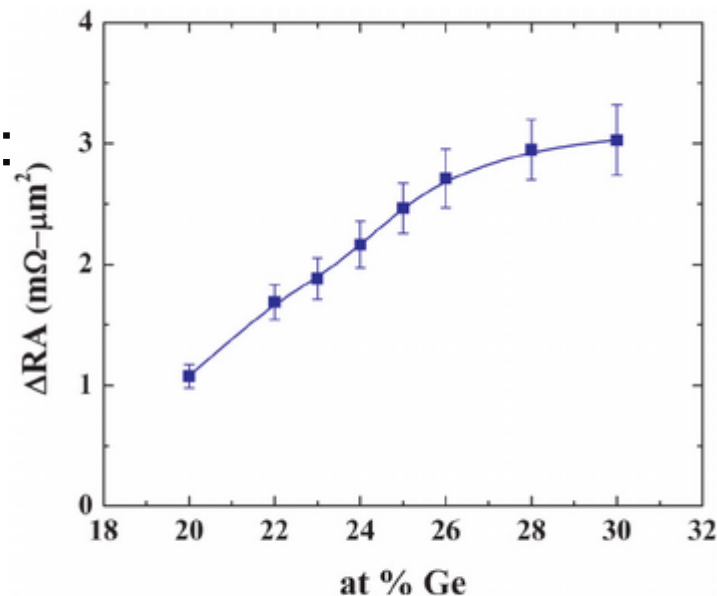


FIG. 7. (Color online) ΔRA versus Ge content for CPP spin valves with Co_2MnGe in the free and pinned layers. High GMR is observed throughout a broad range of compositions. Of particular note is the fact that the GMR is higher for Ge-rich CMG layers, which should show significant deviations from perfect order. Line is a guide to the eye.

JOURNAL OF APPLIED PHYSICS **109**, 093912 (2011)

[Co₂MnGe-based current-perpendicular-to-the-plane giant-magnetoresistance spin-valve sensors for recording head applications](#)

M. J. Carey,¹⁾ S. Maat, S. Chandrashekariah, J. A. Katine, W. Chen, B. York, and J. R. Childress
Hitachi San Jose Research Center, 3403 Yerba Buena Rd., San Jose, California 95135, USA

How to obtain chemical order?

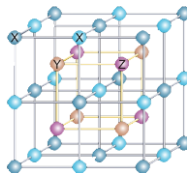


Heated Substrates

- Optimize T_{sub} for order
- Films can be rough depending on underlayer
 - Poor wetting of surface
 - Interdiffusion

Post Deposition Anneal

- Deposit disordered films
- Anneal to obtain order
 - In-situ or ex-situ anneal
- Allows for adjacent layers to be deposited at RT easily
- Favored method of CPP-GMR teams



Optimizing Anneal

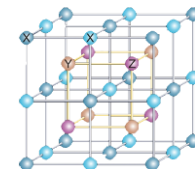
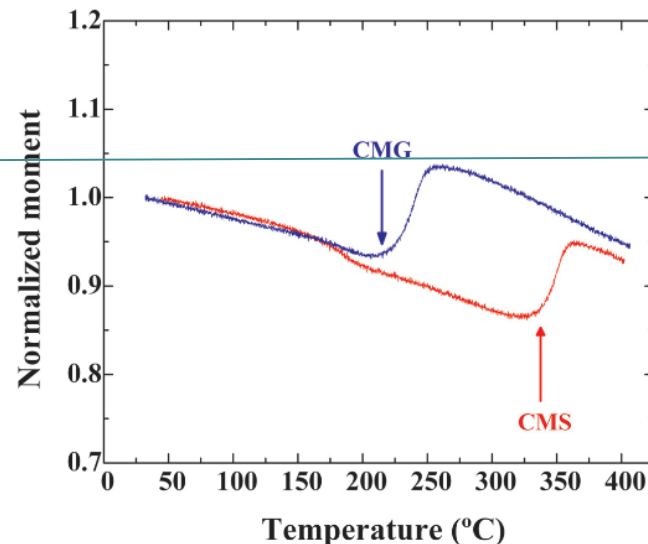


- Each compound has a crystallization temperature (T_{cryst}) and a maximum temperature.
 - E.g. $T_{\text{cryst}}(\text{CMG}) < T_{\text{cryst}}(\text{CMS})$
 - Moment and resistance track crystallization
 - Too high anneal T and Heusler decomposes
 - Pick the compound based on anneal temperature
 - Heads $T \leq 300^\circ\text{C}$
 - MRAM $T \geq 400^\circ\text{C}$

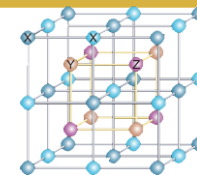
Tracking crystallization by moment

JOURNAL OF APPLIED PHYSICS **109**, 093912 (2011)
Co₂MnGe-based current-perpendicular-to-the-plane giant-magnetoresistance spin-valve sensors for recording head applications

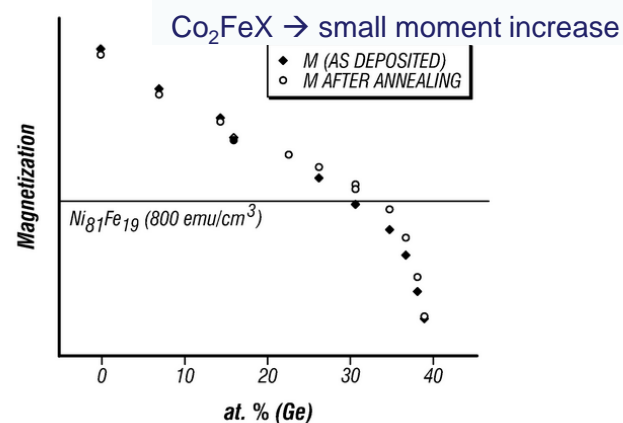
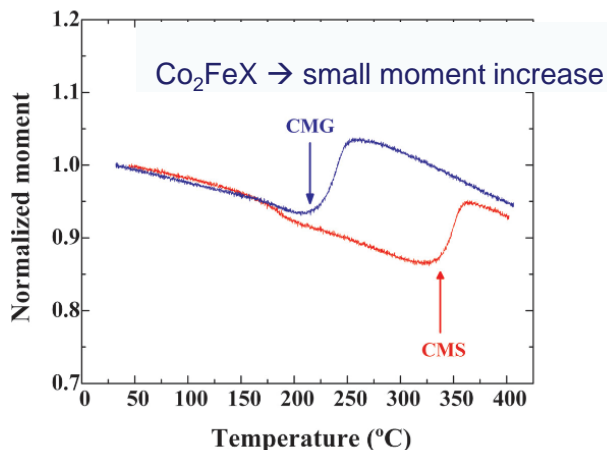
M. J. Carey,¹ S. Maat, S. Chandrashekariah, J. A. Katine, W. Chen, B. York, and J. R. Childress
Hitachi San Jose Research Center, 3403 Yerba Buena Rd., San Jose, California 95135, USA
(Received 27 October 2010; accepted 11 February 2011; published online 10 May 2011)



From a synthesis point of view each Heusler is different



- Co_2MnX alloys
 - Poorly crystallized as deposited
 - Large moment increases with anneal
- Co_2FeX alloys
 - Crystallized as deposited
 - On recrystallization, moment increase is small



Thin Heuslers. Or: Is my GMR dropping due to spin diffusion length or due to structure?

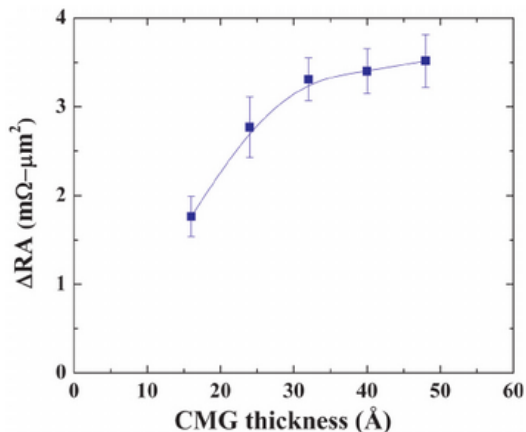


FIG. 8. (Color online) $\Delta R/R$ and ΔRA for simple spin valve with 32 Å Co_2MnGe in the pinned layer and various thickness of Co_2MnGe in the free layer. Line is a guide to the eye. [Ta(50 Å)/Ru(20 Å)/IrMn(70 Å)/ $\text{Co}_{50}\text{Fe}_{50}$ (40 Å)/Ru(8 Å)/ $\text{Co}_{50}\text{Fe}_{50}$ (9 Å)/CMG28(32 Å)/ $\text{Co}_{50}\text{Fe}_{50}$ (5 Å)/Cu(40 Å)/ $\text{Co}_{50}\text{Fe}_{50}$ (5 Å)/CMG28(t Å)/ $\text{Co}_{50}\text{Fe}_{50}$ (5 Å)/Cu(200 Å)/Ru(50 Å)/Ta(25 Å)].

JOURNAL OF APPLIED PHYSICS 109, 093912 (2011)

Co₂MnGe-based current-perpendicular-to-the-plane giant-magnetoresistance spin-valve sensors for recording head applications

M. J. Carey,¹ S. Maat,¹ S. Chandrashekariah,¹ J. A. Katine,¹ W. Chen,¹ B. York,¹ and J. P. Childress
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Giant magnetoresistance in PtMn alloys

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Appl. Phys. Lett., Vol. 84, No. 16, 19 April 2004

TABLE I. Activation energy (E_a) in eV for 100, 150, and 200 Å thick PtMn films. E_a was calculated using two methods: time to reach 50% of total resistance change (t_{50}) and the slope of $\rho(t)$ at t_{50} , $d\rho/dt$.

Å	$E_a(d\rho/dt)$	$E_a(t_{50})$
200	1.54	1.45
150	1.54	1.60
100	2.09	1.82

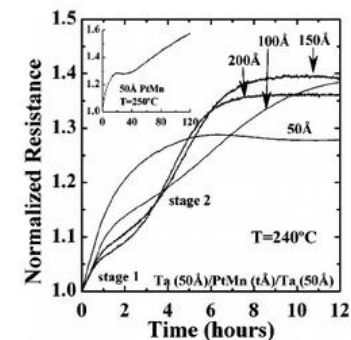


FIG. 4. Normalized resistance vs time for Ta/PtMn/Ta trilayers annealed at 240 °C. Inset shows a longer anneal at 250 °C for a trilayer with 50 Å PtMn.

Example:

Chemical ordering in (non Heusler) PtMn

measured via resistance vs. time at anneal T

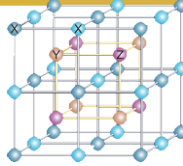
activation energy increases as t_{PtMn} decreases

GMR drop off for thin CMG

Can I use the same recipe for thin Heusler films as for thick?

Answer: Don't count on it!

Optimizing Co_2MnX Heuslers



- Better GMR with amorphous layer under Heusler
 - Ta or CoFeBTa thin layers.
 - GMR increased from 3.5 \rightarrow 5 $\text{m}\Omega\text{-}\mu\text{m}^2$.

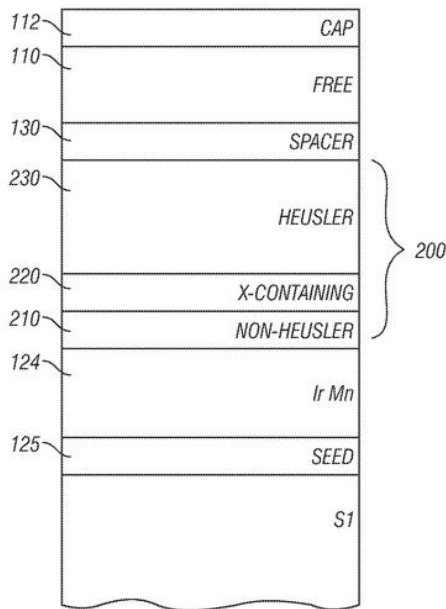


FIG. 5

Insert layer between crystalline seed and Co_2MnX

Current-perpendicular-to-the-plane (cpp) magnetoresistive sensor with multilayer reference layer including a heusler alloy

US 20130236744 A1

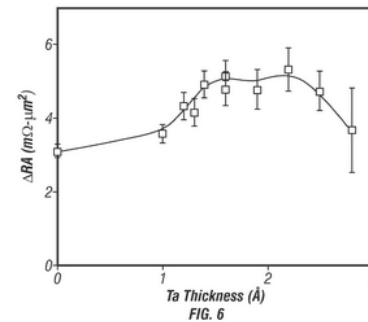


FIG. 6

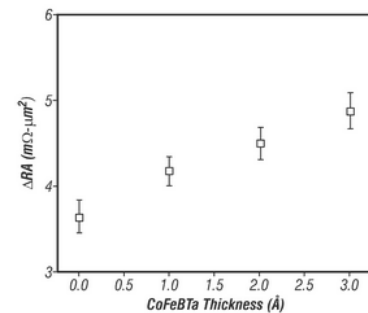


FIG. 7

GMR increases with amorphous layer thickness

Why does GMR increase?

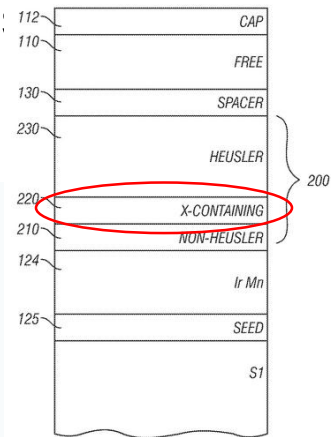
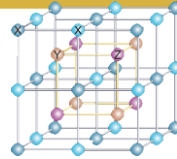


FIG. 5

• Chemical order as measured by XRD increases in annealed samples

- Crystalline quality poor as-deposited
- I.e. amorphous layer insert drives CMG more amorphous as deposited. But this allows for higher quality after anneal.

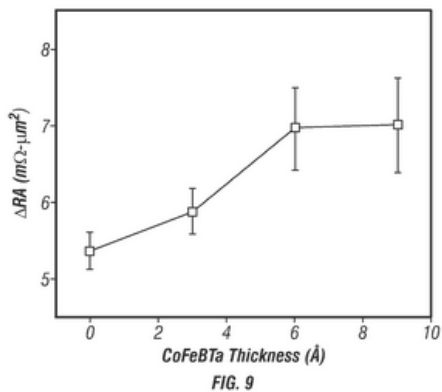


FIG. 9

• Max GMR is comparable to single crystal CMS data.

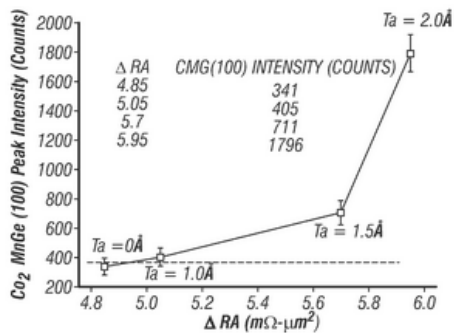


FIG. 10

• Superlattice peak (100) intensity increases with Ta thickness.

→ better chemical order in CMG when deposited nearly amorphous

• GMR increases with (100) Peak intensity

Why does this increase chemical order?

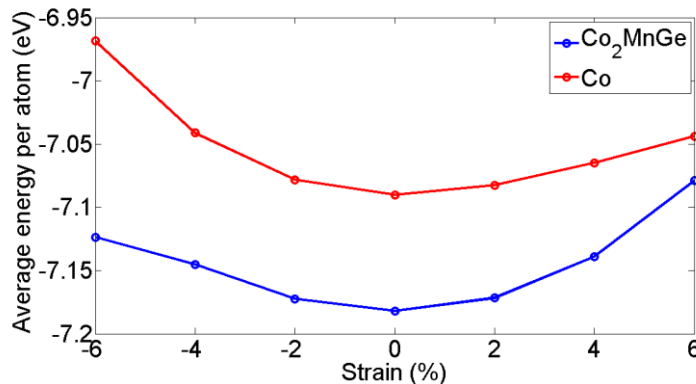


- 1) Makes the Co_2MnX film amorphous as deposited
 - 1) Reduces activation energy for chemical order by combining chemical ordering with crystallization
 - 2) In-situ anneal with Heusler top surface free
→ Nothing to stress Heusler

2) Hypothesis: stress relief

– Amorphous interlayer breaks epitaxy/reduces epitaxial stress

– Groun



tate increases with stress

Kamaram Munira
University of Alabama

Perpendicular Heuslers: interfacial anisotropy



MgO can give iPMA

Seeds can give iPMA
use MgO, Pt, Pd, etc.

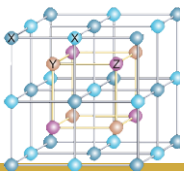
If cubic Heusler is thin enough (~ 1 nm) and has surface anisotropy, one can obtain perpendicular magnetization (similar to CoFeB often used in MRAM)

But is it still a Heusler?

Very thin films hard to characterize

PMA inducing interface materials (Pt, Pd, etc) often increase damping which can negate advantage for MRAM

Interfacial PMA (like that from MgO) has a strong temperature dependence



Tetragonal Heuslers for perpendicular magnetization



“New” class of Heuslers

tetragonal crystal structure (D022)

→ allows for perpendicular anisotropy

High spin polarization (not full half metal)

High Anisotropy

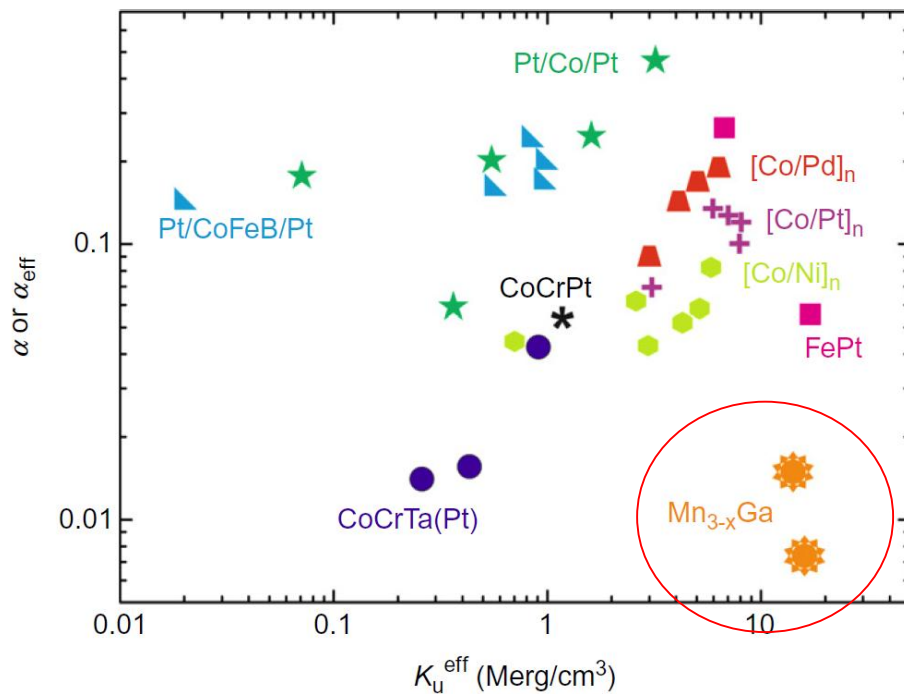
Low damping

The challenge and the future:

Learning how to make this in thin films

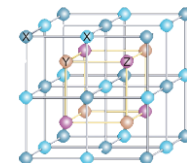
<5nm is tough

roughness



MAGNETIC HEUSLER COMPOUNDS

Tanja Graf^{1,2}, Jürgen Winterlik¹, Lukas Müchler^{1,3}, Gerhard H. Fecher^{1,3}, Claudia Felser^{1,3} and Stuart S.P. Parkin²



Summary



- Heusler compounds offer advantages for CPP-GMR and MRAM
 - High spin polarization (good for CPP-GMR)
 - Low damping (good for MRAM)
- **The past challenge and the future is in fabrication**
 - Especially true for thin films (<3nm)
 - Difficult to fabricate
 - Difficult to characterize
 - Each Heusler and each family have unique fabrication strategies
 - Perpendicular MTJ's present a further challenge
 - Perpendicular moment without compromising damping